ABSTRACT

A method of manufacturing a disk-shaped substrate includes a support step of supporting a disk-shaped substrate with a support portion at a first position on one surface of the disk-shaped substrate; a conveying step of suctioning the disk-shaped substrate with a suction portion at a second position on another surface of the disk-shaped substrate, the second position facing the first position, and conveying the disk-shaped substrate onto a table of a processing device in a state in which the suction portion suctions the other surface; and a processing step of performing processing on the disk-shaped substrate conveyed onto the table.

[FIG .4]